Overview of Device SEE Susceptibility from Heavy Ions

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J. W. Cole, Maj. USAF

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OVERVIEW OF DEVICE SEE SUSCEPTIBILITY FROM HEAVY IONS

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Abstract

A fifth set of heavy ion single event effects (SEE) test data have been collected since the last IEEE publications (1, 2, 3, 4) in December issues for 1985, 1987, 1989 and 1991. Trends in SEE susceptibility (including soft errors and latchup) for state-of-the-art parts are evaluated.

Introduction

Ongoing SEE test programs at JPL ,The Aerospace Corporation, the European Space Agency (ESA), CNES and other organizations are continuing to assess specific part performance for interplanetary and satellite environments and to establish SEE response trends of an ever-increasing body of device data.

In 1985, Nichols et al (Ref. 1) published the first nearly comprehensive listing of SEE test data for 186 parts. This presentation was updated in 1987 (Ref. 2) with the publication of data for 83 additional parts, in 1989 (Ref. 3) with data for 154 parts, and in 1991 (Ref. 4) with data for 182 parts. In this paper, the authors extend the data base for 165 new parts. As before, the data are collected according to technology, function and manufacturer in order to identify trends, generalizations and data gaps.

Testing Approaches

The experimental procedures, such as those used by JPL and The Aerospace Corporation, are evolutionary and are described in detail from time to time in December issues of IEEE Transactions on Nuclear Science (5,6) or in in-house reports. In general, procedures comply with the guidelines for SEE testing set forth by the ASTM F1.11 document (7). They also comply with a JEDEC 13.4 document in preparation, "Test Procedure for the Measurement of Single Event Effects in Semiconductor Devices from Heavy Ion Irradiation."

Organization and Scope of Data

This paper summarizes soft error and latchup experimental test data from the Jet Propulsion Laboratory (JPL), The Aerospace Corporation (A), John Hopkins Applied Physics Laboratory (JH), Centre National D'Etudes Spatiales (CNES, France), European Space Agency (ESA) and other SEE testers. These data are provided directly to JPL or were otherwise made available to the community during the two-year period from January, 1991, through December, 1992. We are pleased to include smaller SEE data sets generated by all U. S. and foreign researchers when these data are made directly available to us. Not included are proprietary data generated by subcontractors who used JPL hardware. Also omitted are now fairly extensive data sets on power transistor burnout obtained by JPL, Rockwell, Boeing and others—such data require a significantly different organization.

The SEE data presented here and in the previous four reports (1,2,3, 4) represent a substantial majority of all test data obtained on SEE throughout the world. Some additional data may exist in other articles of this publication (IEEE-Nuclear Science [Dec. 1993] or this conference's IEEE Workshop Record), in other journals or in published and unpublished presentations of SEE symposia.

The data from all organizations are summarized and collected together even though there are differences in the data from each organization. For example, JPL defines the threshold LET as that value of LET where soft errors are first counted at fluences of 10⁶ ions/cm²; Aerospace now defines their LET threshold as occurring at that point where the measured upset cross section is 0.01 times the measured maximum cross section, CNES reports a threshold at 0.1 times the saturated cross section. JPL's definition virtually guarantees no upset below threshold but results in an overestimate of error rate if the cross section is erroneously assumed to be constant at all LETs greater than the threshold LET. Specifying a threshold LET at a fraction of the saturated cross section attempts to approximate the error rate better, but it introduces an arbitrary factor (to account for the slope of the

cross section vs. LET) and an assumption that the saturated value is known and/or achieved with the highest LET test ions.

The best way to calculate error rates is to use the full curve of cross section vs. LET, which may be available from the parent test organization^[1], and integrate it over all angles and all ions of various LETs. But even this method, which involves the use of a computer, relies critically on what assumptions are made about grazing ion impacts and the dimensions of the device cell's sensitive volume.

All data are presently divided into two tables. Table 1 has been revised to include all SEE (soft error) data for both MOS/CMOS and bipolar devices. Table 2 exhibits data for "Latchup Tests Only". All data listed here represent a substantial abbreviation and ignore statistical features altogether. LET limits are for nominal effective values without correction for degradation that can occur when an ion traverses device overlayers. Gold data, in particular, are seldom as damaging as one would expect on the basis of nominal LET and such data are labeled when known, and Au testing is usually not recommended. SEE tests use a dynamic nominal bias (often 4.5 or 5.0 V); latchup tests are usually performed at the maximum value of the nominal bias range (e.g. 5.5V) -- a condition usually (but not always) enhancing the possibility of latchup. Reported data were taken at room temperature or ambient temperature; higher test temperature measurements may exist for some parts. In some instances, data on transients is noted, which may or may or may not impact electronics down the line. Hence, a system designer interested in a specific part is again urged to contact the appropriate test organization for further information.

Users are cautioned that manufacturers (Appendix I defines manufacturer abbreviations) may often change their process, and resultant SEE susceptibility, without changing the part number or notifying tester organizations. Hence, a test of flight parts is always a good policy.

Trends & Limitations

Trends and device comparisons in the recent data are offered in the "Remarks" column of Tables 1 and 2 and in the following section. However, the organized tabular format is designed to facilitate comparisons. Special studies (such as variation of SEE response with temperature) or a comparison between high energy (GANIL) heavy ion data and that from the lower energy Berkeley 88-inch cyclotron and BNL Van de Graaff are beyond the scope of this presentation. In addition, test data for the whole class of catastrophic failures of power transistors, both MOSFET and bipolar, has recently been organized by Nichols under a substantially different format.

Some colleagues have commented that a measure of the shape of the cross sections vs. LET might be useful-- such as given by a tabulation of the Weibull parameters. Others point out that it may be more difficult to assure that such parameters are properly derived and applied than it is to calculate SEE rates directly from known (and readily available) experimental cross sections.

Program managers concerned with critical system reliability issues will ultimately need an appropriate set of cross sectional data to assess statistical features and focus on specific answers. Ballpark estimates will also have a place, however, by helping assure that expensive experiments are limited to only critical SEE issues.

An Evaluation of SEE Data

<u>Microprocessors</u>

JPL tested a large body of SEE data for microprocessors this year, mostly with 16-bit and 32-bit capability. Soft error thresholds are consistently low for all high-capability machines, with LET(th) ranging from approximately 1 to 10 MeV/(mg/cm²). Important exceptions are two 16-bit devices by Marconi (GEC-Plessey), using their well-established SEE-resistant SOS technology. Most microprocessors are not very susceptible to latchup although there are exceptions (e.g. the IDT R3000 and R3000A.) The Intel CHMOSIV technology is marginally susceptible to latchup, whereas its earlier CHMOSIII technology was not. There is a very large set of data from ESA and Harris on the R3000 and R3000A RISC developed by many manufacturers.

Questions raised last year regarding the best approach to microprocessor testing remain open. The purists argue that static testing of known registers in a known state is the best approach to understanding SEE effects. JPL presently pursues this view and has demonstrated that not all elements of a microprocessor are equally SEE-susceptible. The pragmatists claim that testing with dynamic programs (the more the better) will usually show that static tests provide an unrealistic worst case.

Some data taken by European groups at GANIL, the higher-energy (10 to 100 MeV/amu) cyclotron in France, are available. The results suggest that these ions, which are more representative of interplanetary cosmic rays, are more damaging than the familiar lower-energy (2 MeV/amu) ions provided by Brookhaven's Van de Graaff and Berkeley's 88-inch cyclotron. Direct comparisons between energy regimes are few.

It will also be observed in Table 1 that there are data for several controllers and processors of various types. They have similarly low soft error thresholds [< 10 MeV/(mg/cm²)] and varying latchup susceptibility.

^[1] JPL data, including more recent results, may be accessed directly from JPL's computer data base, RADATA.

Analog-to-Digital Converters (ADCs)

There are several data sets for ADCs and data for two digital-to-analog converters (DACs). Much of the data were taken by JPL in a quest for the least SEE-susceptible 12-bit ADC. The MAXIM devices were clear standouts in this subcategory, but one observes that a completely hard ADC or DAC is a rarity. This is one device type where knowledge of how the device ties in with the system is an all-important consideration in assessing its ultimate suitability.

Static RAMs (SRAMs)

There is much new data to add to the accumulation for SRAMS--with device sizes up to 4 Mbits. All devices employ variations of CMOS technology this test period, and SOI and SOS offer markedly superior resistance to soft errors and latchup. Epi technology (where the epi layer is less than ~10 microns thick) is a good guarantee against latchup but offers no significant advantages against soft errors. A tendency toward stuck bits was observed in the 0.5 micron feature-size Hitachi 4 M SRAM.

Other RAMS

ESA tested a large set of 4M DRAMs and observed a consistent very low soft error threshold typical of this device function. Some non-volatile RAMs were tested-- with two Ferroelectric RAMs (FRAMs) for the first time. Some bipolar and CMOS PROMs exhibited relatively high SEU thresholds, but one should note that PROMs are occasionally susceptible to latchup.

Gate Arrays & Bus Controllers

Several gate arrays, configured in different ways, were tested. It is difficult to sort out the large variability in soft error threshold-- even among devices made by the same manufacturer. It is encouraging that no cases of latchup were reported.

Latchup Data

Tests for latchup only are much easier to set up than those designed to measure soft errors as well. Such data are given separately in Table 2-- primarily for devices with different variations of CMOS technology. It has so far held true that bipolar devices will not latchup with heavy ions. However, latchup has occurred in bipolar devices when exposed to high intensity gamma pulses, and the requisite pnpn parasitic structure exists.

The LET thresholds listed in Table 2 are for latchup only, and cross section data is rarer because of the difficulty in obtaining repeat measurements where catastrophic burnout and overheating may occur. Also presented are data for GANIL which appears to have a devastating effect—including latchup in several devices with epi technology. Once again a need to compare data on identical parts for both high energy GANIL ions and lower-energy ions is manifest.

JPL was able to employ Cf-252 usefully for the first time-- as a screen to reject some ADCs because of latchup. It is cautioned, however, that Cf-252 can never be used to pass a part for latchup because of the possibility that the fission ions do not have adequate range to maintain an adequate LET while generating a funnel at the well-substrate junction.

Latchup observed by MIT-Lincoln Lab in the NSC driver/receivers 26C31 & 26C32, a pair of linear devices, is explained by Sferrino [9]. He notes that the chips have tristated digital outputs, comprising an npn and pnp transistor in series-- the familiar structure for latchup paths. This result suggests that other transistor arrangements, such as siliconcontrolled-rectifiers, may be susceptible to latchup.

Conclusions

The new data presented here can be combined with data given in References (1, 2, 3 and 4) to develop certain generalizations useful for protecting flight electronics from SEE. Hard technologies and unacceptably soft technologies can be flagged. In some instances, specific tested parts can be taken as candidates for key functions-- such as microprocessing or memory. As always with radiation test data, specific test data for qualified flight parts is recommended for critical applications. Calculations of accurate SEE rates will require the assistance of a computer code, a well-defined environment [in terms of flux vs. LET] and a complete device characterization [cross section vs. LET at the appropriate temperature.] Evaluation of catastrophic effects requires its own statistical treatment, in which flares are considered. The recent concern of JPL and others with power transistor burnout and single event gate rupture is beyond the scope of this compendium.

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	Appendix I - Manufacturer Abbreviations	TOS TRW	Toshiba TRW Inc.
ACT	Actel Corp.	UTM	United Technologies Microelectronics Center
ADA	Advanced Analog	WAF	Waferscale
ADA ADI	Analog Devices Inc.	XIC	Xicor Inc.
		XIL	Xilinx Corp.
ALS	Allied Signal	ZOR	Zoran
ALT	Altera Corp.	ZYR	Zyrel
AMD	Advanced Microdevices Corp.		
ATM	Atmel		
ATT	American Tel & Tel		Appendix II - Test Organizations
BUB	Burr-Brown Research		1.000 0.000.000
CRY	Crystal Semiconductor Inc.	Α	The Aerospace Corporation; El Segundo, CA
CYP	Cypress Corp.	BPS	Boeing Physical Sciences Research Center, Seattle
DAT	Datel	CLM	Clemson University; Clemson, SC
DDC	DDC ILC Data Device Corp.		
EDI	EDI Corp.	CNES	Centre National d'Etudes Spatiales; Toulouse, France
FER	Ferranti	ESA	European Space Agency several facilities
FUI	Fujitsu Ltd.	GD	General Dynamics
GEC	GÉ	GDD	NASA Goddard Space Flight Center; Greenbelt, MD
HAR	Harris Corp., Semiconductor Div.	GE	GETSCO, Philadelphia
HIT	Hitachi Ltd.	HAR	Harris Semiconductor, Melbourne, FL
HON	Honeywell Inc.	HON	Honeywell, Clearwater, FL
IBM	IBM	J	Jet Propulsion Laboratory (JPL); Pasadena, CA
	Integrated Device Technologies, Inc.	JH	John Hopkins Applied Physics Laboratory; Laurel,
IDT			MD
INM	INMOS Corporation	LIN	Lincoln Laboratories, M. I. T.; Cambridge, MA
INT	Intel Corp.	MMS	Matra Marconi Space; Vélizy, France
LDI	Logic Devices Inc.		NASA
LTC	Linear Technology Corp.	NRL	Naval Research Laboratories, Washington D. C.
LSI	LSI Logic Corp.	R	Rockwell International (Anaheim, CA)
MED	Marconi Electronic Devices	SSS	S-Cubed, San Diego
MCN	Micron Technologies	TRW	TRW Space and Defense Sector (Los Angeles, CA)
MIT	Mitsubishi	11(11	11t (opaco ana potonso poetas (200 i ingolos, el 1)
MMI	Monolithic Memories Inc.		
MOT	Motorola Semiconductor Products Inc.		Appendix III – Test Facilities
MPS	Micro Power System		11ppc/14434 111 — 1 cos 1 4 cossido
MTA	Matra Harris SemiconductorMXM MAXIM	88-in.	= 88-inch cyclotron, Lawrence Berkeley
NAT	Natel Engineering	- OO-MI	Laboratory
NEC	Nippon Electric Corp.	BNL	= Tandem Van de Graaff, Brookhaven National
NSC	National Semiconductor Corp.	DINL	
OWI	Omni-Wave, Inc.	CE DED	Laboratory, Long Island, NY
PFS	Performance Semiconductor Corp.		= A Cf-252 fission source
PLS	Plessey Semiconductors	ESA	= European Space Agency— several sites
PMI	Precision Monolithics, Inc.		C = Cyclotron for Heavy Ions; Caen, France
RAY	Raytheon Co., Semiconductor Divison	HAR	= Van de Graaff at Harwell, England
RCA	Radio Corporation of America	IPN	= Tandem Van de Graaff, Institut de Physique
RTN	Ramtron		Nucleaire; Orsay, France
SAM	Samsung	UW	 Tandem Van de Graaff, University of
SEI	Seiko		Washington, Seattle
SEQ	SEEQ Technology Inc.		
SGN	Signetics Corp.		
SIE	Siemens Inc.		
SIL	Siliconix		References
SIP	Sipex		-
			K. Nichols, W. E. Price, W. A. Kolasinski, R. Koga, J. C.
SLG	Silicon General		J. T. Blandford, A. E. Waskiewicz, "Trends in Parts
SNL	Sandia National Laboratories		tibility to Single Event Upset from Heavy Ions," IEEE Trans.
SNY	Sony Corp.	on Nuc	. Sci., <u>NS-32</u> , No. 6, 4189 (Dec. 1985)
SOR	SOREP		
TEL	Teledyne Crystalonics	[2] D.	K. Nichols, L. S. Smith, W. E. Price, R. Koga, W. A.
TIX	Texas Instruments Inc.		uski, "Recent Trends in Parts SEU Susceptibility from Heavy
TMS	Thomson Military & Space, France	ions , i	EEE Trans on Nuc. Sci., NS-34, No. 6, 1332 (Dec. 1987)

- [3] D. K. Nichols, L. S. (Ted) Smith, George A. Soli, R. Koga, W. A. Kolasinski, "Latest Trends in Parts SEP Susceptibility from Heavy Ions," IEEE Trans. on Nuc. Sci., NS-36, No. 6, 2388 (Dec. 1989)
- [4] D. K. Nichols, L. S. Smith, H. R. Schwartz, G. Soli, K. Watson, R. Koga, W. R. Crain, K. B. Crawford, S. J. Hansel and D. D. Lau, "Update on Parts SEE Susceptibility from Heavy Ions," IEEE Trans, on Nuc. Sci., NS-38, No. 6, 1529 (Dec. 1991)
- [5] R. Koga, W. A. Kolasinski, J.V. Osborn, J. H. Elder & R. Chitty, "SEU Test Techniques..." IEEE Trans. on Nuc. Sci., <u>NS-35</u>, No. 6. 1638 (Dec. 1988)
- [6] D. K. Nichols, J. R. Coss, L. S. Smith, B. Rax, M. Huebner, K. Watson, "Full Temperature Characterization of Two Microprocessor Technologies", ibid p 1619 (Dec. 1988)
- [7] ASTM Designation: F 1192-90, "Standard Guide for the Measurement of SEP Induced by Heavy Ion Irradiation of Semiconductor Devices" ASTM, 1919 Race St., Philadelphia, Pa. 19103

- [8] R. Koga, W. R. Chin, S. J. Hansel, S. D. Pinkerton, T. K. Tsubota, "The Impact of ASIC Devices on the SEU Vulnerability of Space-Borne Computers", Preprint, IEEE, Trans. on Nuc. Sci., NS-39, No. 6 (Dec. 1992)
- [9] Vince Sferrino, MIT Lincoln Lab, private communication.

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Reference herein to any specific commercial product, process, or service by trade name, trademark, manufacturer, or otherwise, does not constitute or imply its endorsement by the United States Government or the Jet Propulsion Laboratory, California Institute of Technology.

TABLE 1. SEU DATA - 1991-1992 (MOS & BIPOLAR DEVICES)

Remarks	7/91. No LU-120. See also J: 6/87.	9/91. [1] RAM data at high LET.	11/90, Chapula.	Harboe-Sorensen IEEE NS 7/92	Harboe-Sorensen IEEE NS 7/92	Harboe-Sorensen IEEE NS 7/92	Test data taken with low energy Harwell Tandem Van de G. gives much smaller cross sections than preceding data.	9/92 [1]=AX, BP, ES [2] = Relocation, SPR, DPR, TCR		6/92. No LU with Au @ 42° angle. See preceding.	No LUS 100, 10/91	No LU5100, 7/91	92IEEE Workshop. J. Kinnison (7/92)		6/92. LU>175. [1] GEC-Plessey	Consistent with JPL data of 5/89 2.5 µm.	No LU. 92IEEE Workshop (7/92)	7/91. LU(th)<<24.	5 & 7/91. LU=40.	7/92. LU=27. 7E-5 cm².	92IEEE Workshop, 1=register test	92IEEE Workshop. 1=register test	5/91. No LU-120. D. Vail (HAR). Table 2. VLSI MIPS RISC.	5/91. No LU-120. D. Vall (HAR). Table 2. VLSI MIPS RISC.	LU(th)<3.3. RISC Harboe-Sorensen 92IEEE Workshop	No LU>60. RISC Harboe-Sorensen. 92IEEE Workshop	No LU>60. RISC Harboe-Sorensen. 92IEEE Workshop	No LU>60. RISC Harboe-Sorensen. 92IEEE Workshop	LU(th)=60. RISC Harboe-Sorensen. 92IEEE Workshop	LU(th)=27. RISC Harboe-Sorensen. 92IEEB Workshop	LU(th)=60. RISC Harboe-Sorensen. 92IEEE Workshop	No LU>60. RISC Harboe-Sorensen. 92IEEE Workshop	No LU-60. RISC Harboe-Sorensen. 92IEEE Workshop	92IEEE Workshop Dufour. 7/92	8/92 This is non-hard version of 80C51. Oberg.	[1]=IRAWDRAM LU=10; 1E-3 cm².
Facility****	BNL	88-In	GANIL	GANIL	GANIL	GANIL	an de G. g	BN		BNL	88-in	88-In.	BN	i	BN BN	GANIL	NA Na	BNL	BN.	BNL	N N	<u>N</u>	BNL	BNL	BNF	BNL	BNF BNF	BNL	BNL	BNF	BNL	BN	BNF	GANIL	88-In	
Section Per Bit (sq µm)	65 @ LET=60	200	i	1000 @ LET=9	2000 @ LET=9	3000 @ LET=9	Harwell Tandem V	250[1]; 450[2]	[LET=61]	20[LET=13]	ı	4000	ın		No upset	No upset	ı		100	ı	ı	ı	ı	1	ı	300	100	100	120	≯ 100	100	120	200		400[1]	
Device Cross Section (cm²)***	١,	4E-3(1)	1E.2	ı	•	:	th low energy	•		1	15.3	1	3E-4 [MMU @	יינו אמן יינו אמן	No upset	No upset	1	1	ı	ı	1E-2 ^[1]	1E-2 ^[1]	15.3	15.3	ı	ı	ı	ı		ı	•	1	1	2E-3	1	
Effective LET** Threshold	8	8	6 0	7	7	7	data taken wi	Ħ		~	12	우	6	ļ	175	×60	150(Au)	>>2.5	3.5±1	•	4.7	4.7	<3.4	ဖ		"?	ౚ	1 0	ę	æ	&	ę	6	6	~3[1% sat]	
Bits	95 bits tested	~2K	1	ı	ı	1	Test	009~		510 of 752	ı	ı	all 3 chips		ı	1	ı	1	272	1	varies	varies	~1300	~1300	736 (23 reg)	736 (23 reg)	736 (23 reg)	736 (23 reg)	736 (23 reg)	736 (23 reg)	736 (23 reg)	736 (23 reg)	736 (23 reg)	1	~2300 total	
Mr.	FAR	HAR	ΧE	볼	HAR	HAH	HAR	¥		¥	볼	¥	PFS		MED[1]	<u>Q</u>	HAR	AMD	¥	¥	MOT	MOT	PFS	SE	ם	IS T	PFS	뿞	REC	ᄓ	rs T	PFS	뿘	ısı	¥	
Technology	CMOS/epi	CMOS/epi	Bipolar(I ² L)	CMOS/epi	CMOS/epi Mask 1860	CMOS/epi Mask 3584	CMOS/epi Masks 1860	& 1750	CHMOS III	CHIMOS III	CMOS	CINOS	CMOS/SOS 3-chips	0000010	CMOS/SOS	CMOS/SOS	TSOS-4 process	CINOS	CHINOSIV	CHIMOSIV	CMOS/epi	CMOS/bulk	Adv. CMOS	Adv. CMOS	CEMOS IV	CINOS	PACE	Adv. CMOS	CMOS	CEMOS V	HCMOS	PACE II	Adv. CMOS	CMOS	CHINOS III	
Function	MicroP 8-bit	Peripheral to 8085	MicroP 16-bit	MkroP 16-bit	MicroP 16-bit	MicroP 16-bit	MicroP 16-bit		MicroP 16-bit	MicroP 16-bit	MicroP 16-bit	UART	MicroP 16-bit		Microf 16-bit	MicroP 16-bit	MicroP 16-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	MicroP 32-bit	DCT Proc.	MicroC 8-bit	
Device	80С85ПН	81C55RH	SBP9989	80C86-2/B	8008	8008	8008		M80C186	80C188	MG80C186	MD82510	1750A	01170	MA31/50	MAS281	RTX2010RH	80386	80386	80386	68020	68020	H3000	R3000	R3000	R3000	R3000	H3000	R3000	R3000A	H3000A	R3000A	H3000A	L64730	87C51FB/	87C51FC
Test Org.****	-	7	CNES	ESA	ESA	ESA	ESA		-	병	∢	4	=	-	-	ESA	픙	-	7	000	CNES	CNES	HAR	HAR	ESA	ESA	ESA	ESA	ESA	ESA	ESA	ESA	ESA	CNES	BPS	

^{*} See listing of abbreviations in Appendix I.

** LET is Linear Energy Transfer = the density of ionization along an ion's path in MeV/(mg/cm²). The cosine law for beam angle is applied where valid to obtain "effective" LET.

**** See listing of abbreviations in Appendix III.

**** See listing of abbreviations in Appendix III.

**** See listing of abbreviations in Appendix II.

**** Unless otherwise noted, the cross section (upsets/fluence per device) is given for 240-380 MeV Kr or Br at normal incidence, having an LET=36 to 40 MeV/(mg/cm²).

TABLE 1. (Cont'd)

Remarks	IEEE92 Workshop Record, p1.	No LU>27. Harboe-Sorensen 92IEEE Workshop	LU=27. Harboe-Sorensen 92IEEE Workshop	No LU>27. Harboe-Sorensen 92IEEE Workshop	No LU>60. Harboe-Sorensen 92IEEE Workshop	10/92. See Table 2. LU(th)=24 to 37.	92IEEE Workshop. 1=register test	92/EEE Workshop. 1-register test	Dufour, 92IEEE Workshop. (1)=MPY test program;	(2)=RAM test. LU=31; 1E-4 cm ² .	LU=13.5; 1E-4 cm ² .	, having a different substrate, exists with No LU>120. (See J. Kinnison, IEEE NS Dec 91, p 1398). Availability not known.	No LU>>38, but a 17 µm epi std. production part	latched up easily. M. DeLaus – 1/91.	LU=12; 2E-5 cm ² . Harboe-Sorensen IEEE NS Dec 92,	p 441. See above.	1291. No LU>110.	1/92. No LU> 89.	2/92.	10/92. DC: 9142 No LU>>37. WP-02	No LU-100. 10/92	LU=7;1.3E-5 cm ² . [1]=bipolar, but LU raises questions	of possible CMOS also. DC: 9142 & 9222 WP-02. 10/92	12/91. See Table 2: J: No LU>120. 11/92	2/91. Flion only.	7 & 9/91. No LUI>175. See Table 2.		11/92	11/92	No LU>>37. 10/92 DC: 9210	11/92 See Below. No LU>120 at 80° C.	Earlier DC is latchable.	11/92 LU(th)=30. See above.	9/91. No LU>110.	9/91. No LU5110.	11/92. No LU-120.	11/92. No LU5120.	7/91. LU LET<<40.	7/91. LU LET<<40.	9/92, No LU>104	No LUS-100, 1/92
Facility****	BNL	BNL	BNL	BNL	BNL	BNL	Ndi	M	GANIL		BNL	ilson, lEEE	BNL		<u>Z</u>		BNL	BNL	₹	BNL	88-in	BNL		88-in	₹	BNL &	98-in	BNL	BNL	BN.	BNL		BN	88-In	88-In	BNL	BN.	BNF	BNF	BNF	88-in
Cross Section Per Bit (sq µm)	1	×100	100	£	200	20[LET=24]		ı	1		ı	5120. (See J. Kinr	1		300		ı	1	ı		1	ı		ı	1	ı		ı	ı	ı	ı		ı	ı	1	1	1	ı	ı	1	
Device Cross Section (cm ²)***	×1.54	ı	1	1	ı	ı	1E-2 ^[1]	1E-2[^{1]}	4E-4	2E-2	5E-3	xists with No LU	3E-4		ı		5E-5	4E-5	>2E-4	1.4E-4	2E-4	3.2E-4		1E-3	>1E-4[LET=10]	2E-4[8 MSB's]		>2E-4	>2E-4	8E-5	×1E4		1	1	ı	>5E-4	×1E-3	ı	•	15-3	5E-4
Effective LET** Threshold	₽	\$	æ	ę	á	4	က	က	7	7	5	substrate, e	_		∞		<13	\$	\$	ষ	ĸ	\$		7	~	9		8	ន	2	\$		•	ç	Q	8	ņ	6 *	6	₹ >	6
Bits	006	1024 (32 reg.)	1024 (32 reg.)	1024 (32 reg.)	1024 (32 reg.)	all 640	varies	varies	[Ref 1]	[Ref 2]	1	having a different	1		531		16 tested	i	ı	ı	ı			ŧ	1	ı		ł	ı	•	ı		1	1	ı	1	,	ı	ı	ı	
·.	¥	<u>5</u>	<u>s</u>	PFS	뿛	¥	MOT	MOT	TIX(Fr?)		ΑĐ	e above,	ADI		ADI	•	NAT	¥	ADI	₹	¥	ADI		Sd ₹	ADI	ADI		HXH.	MXM	HAH	HAR		HAH	ADI	ΥDΙ	ADI	MXM	808	BOB	ADI	읈
Technology	CHMOS III	CEMOS V	HCMOS		VAdv. CMOS	CHIMOS IV	CMOS/epi	CMOS	CMOS		CMOS/epi commercial ADI	perimental version of tl	CMOS/epi 13 µm		CMOS/epi 12.5 µm		Hybrid RH CMOS	CMOS	Bipolar (I 2 L)		BICMOS	Ξ		CMOS	CMOS	CMOS		BICMOS	Bipolar/CMOS?	CMOS	DC9205		DC9028	BIMOS	Bipolar (Two chip)	BIMOS	BICMOS	Bipolar/CMOS	Bipolar/CMOS	BICMOS	CMOS Hybrid
Function	DMA Cont. 32-bit	FP Accel. Coprocessor CEMOS V	FP Accel. Coprocessor HCMOS	FP Accel. Coprocessor	FP Accel, Coprocessor \Adv. CMOS	Coprocessor	FP Coproc. 32-bit	FP Coproc. 32-bit	DSP		DSP	JH also reports that an experimental version of the above	DSP		DSP		Resolver Dig. Conv.	8-bit DAC	8-bit DAC	12-bit DAC	12-bit DAC	8-bit ADC Flash		8-bit ADC Flash	8-bit ADC	12-bit ADC		12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC		12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	14-bit ADC	16-bit ADC
Device	82380	_				80387-16	68882	68882	TMS320C25		ADSP2100A	=	ADSP2100A		ADSP2100A		HSRD1056	DAC8408	AD558	PM7545	DAC8412	AD9048TQ		MP7684	AD7824	AD7672B		MX7672	MX7572	HI574	HI674ALD		HI674ASD	AD574A	AD674A	AD674B	MX674A	ADC574A	ADC674	AD7872	НS9576RH
Test Org.****	GDD	ESA	ESA	ESA	ESA	띪	CNES	CNES			٦ =		NRL A		ESA A		7	SSS	BPS	N S	<	NO.		<	BPS	7		7	7	NO P	7		7	7	7	7	7	7	7	7	4

TABLE 1. (Cont'd)

																ace data.									sat.																,
Remarks	92IEEE Workshop Kinntson	92IEEE Workshop Kinnison "Alinistch"	LU=38, 9/92. Compare Table 2	McKulty. 1919	11=15:1E:3 cm ² 19:09	LU=10: 1E-4 cm ² . 12/92	JEEE NS 6/92 D450 [1]=With variable R	IEEE NS 6/92 p450 [1]=with variable R.	5/91. No LU>90 up to 125 dea C.	DC=? See above.	No LU. W. Newman 10/91, [1]=Rad Hard CMOS/SOS	3.0 µm technology	3.0 µm technology	1.5 µm technology	6/92. Development SRAM. No LU>115.	1/91. No LU reported IEEE 91. Compare '87. Aerospace data.	[1]=Factor of 100 lower for high R. No LU>100, 6/92	No LUS-100, 7/91	LU(th)=23; 1E-2 cm ² Dufour, 92IEE Workshop	7/92 Multiple upsets	Date Code 9133	<5/91. DC8116 No LU>26. Possible multiple	errors/strike. (1)=Worst case all 1's	Date Code 9125. [1]=at 10% of sat. See Table 2.	Date Code 9101 (1)= Worst case all 1's [2]=at 10% of sat.	(1)=low current resistor process. [2]=at 10% of sat.	IEEE91. No LU>100. Multiple errors/strike. A high	resistivity DUT: SEU cross=~1E-2 cm².	9/91. No LU>110. No date code.	8/91. LU=50; 4E-4 cm². [1]=at 10% of sat.	Compare earlier CNES data.	1992. Engr. sample	9/91. No LU>50. R. Ecoffet	12/90. 1µm.; No LU at LET=116		Date Code 8933	Date Code 9151	No LU>100. 10/92	LU=8; 8E-3 cm², 10/92	LU=45; 2E-5 cm ² , 10/92	LU=55; 2E-5 cm². 2/90 (Corrected)
Facility****	BN BN		BNL	BNL	88-in	88-in	BNL	NH H	BN.	BNF	BNL	88-In	88-in	88-in	BNL	M	88-In	88-in	GANIL		<u>M</u>	N		N <u>d</u>	NA.	<u>R</u>	98-in		88-in	N <u>d</u>		Ndi	Nd	BNL;	GANIL/IPN	M N	IPN	88-In	88-In	88-In	88-in
Cross Section Per Bit (sq µm)		ſ	94		8	8	92	8	1	ı	1	2 @ LET=75	5@LET=75	2 @ LET=120	No upset	100	ı	ı	ı	•		1		1	1	ı	ı		•	300			ı	88		ı	ı	ı	•		ı
Device Cross Section (cm²)***	86.4	35-3	4.2E-3	5E-6 @ LET=24	8E-3	7E-3	1	1	ı	ı	ı	1	ı	ı	No upset	ı	-1(I)	6.0	9.0		0.5	0.6[1]		1.8	2.0	2E-3	7		2E-2	0.2			0.4	t		0.2	1	8E-2	0.1	0.2	8E-2
Effective LET** Threshold	22	o	3.5	8	ın	~	#	25 to 40	8	98	≯138	7	8	9-	>115	~	€,	က	⊽		4.5	~	•	<u>.</u>	S. 2	<7 ¹²	4		8	2.5; 10[1]	;	6[10% sat]	9[10% sat]	10		2	×114	4	က	Ç	e
Bits	64x9	5120	1Kx9	2Kx8	2Kx8	2Kx8	2Kx8	2Kx8	8Kx8	8Kx8	64	16Kx1	2Kx8	64Kx1	64Kx1	32Kx8	256Kx1	32Kx8	32Kx8		1Mc1	128Kx8		128Kx8	128Kx8	128Kx8	128Kx8		128Kx8	8Kx8		32Kx8	8Kx8	8Kx8		9Kx8	8Kx8	2Kx8	вкхв	128Kx8	128Kx8
Mr.	NSC	NSC	ΤQI	¥	[0	CYP	HON	HOH	P	NOH NOH	HAR	WED	MED	MED	WB.		SC SC	S	SC SC		Z ¥	WCN		MCN	SC	Ş	NCN MCN			MTA	į	MTA	MTA	MTA		MTA	TINS	百	<u>D</u>	MOT	SNY
Technology	CMOS/epi	CMOS/epi	CIMOS/epi	CMOS	CMOS/NMOS	CMOS/NMOS	CMOS[1]	CMOS[1]	CMOS/SOI DC9029	CMOS/epi	Std Cell [1]	CMOS/SOS	CMOS/SOS	CMOS/SOS	CMOS/epi	NMOS/CMOS	CMOS/NMOS	CMOS/epl	CMOS 2M-2P		CIMOS	CMOS/epi		CMOS	CMOS/epi	CMOS	CMOS/epi NMOS		CMOS/epi [new version]	CMOS/epi [12 µm]		SCMOS	SCMOS Final process	SCMOS/epi		CMOS/epi	<u></u>	CMOS(V)NMOS	CMOS(V)/NMOS	CMOS/NMOS	CMOS/NIMOS
Function	얦	FIF0	FIFO (10 µm)	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SRAM	SHAM	SRAM	SRAM	SRAM	SRAM .	SHAM	SRAM	SRAM	SRAM	,	SRAM	SRAM		SHAM	SRAM	SRAM	SRAM		SHAM	SHA			SRAM	SRAM			SHAM			SHAM	SRAM
Device	54AC708	74AC725	7202RE	HC5517A	L6116	CYPC128A	HC6116	HC6216	HX6364	HC6364	TS054	MA6167	MA6116	MA9187	IBM6401	EDH8832C	MT5C256	MT5C2568	MT5C2568C		MT5C1001	MT5C1008		M15C1008	MT5C1008	MT5C1008	MT5C1008		MI 5C1008C	HMS50561	010101	HM05050	HM65664	HM1-65664		HM65641	TS4H6408	IDT7052	IDT7164	MCM6226	CXK581000P-10L
Test Org.""	픙	丐	QQD	ੂ ਨੂ	⋖	⋖	HOH	P N P	7	P P	HAH	ESA	ESA	ESA	-,	ESA	⋖ ·	⋖	SE SE		CNES	CNES		SHES	CNES	CNES	⋖			SES.	į	3		NASA		CNES	CNES	⋖	⋖	⋖	χ «

TABLE 1. (Cont'd)

1			1																				1							 •									
Remarks	LU=30; 5E-5 cm ² . 10/92	9/92. No LU>90 Stuck bits seen.		No LU>82, 4/92		LU(th)=25; 1E-4 cm ² dynamic test. 4/92	No LU-82. 4/92	No LUS 50 RADECS 91	No LUS-40 RADECS91	No LU≻40 RADECS91 [1]≃Engr. sample.	See also Table 2 & below.	No LU-100. 3/92	No LUS 50 RADECS 91	No LUS-40 RADECS91	No LUS-40 RADECS91	No LUS-40 RADECS91	No LUS-40 RADECS91		(1) = SHAM comiguration.	(1) = EEPROM configuration.	6/92. LU LET<<30	6/92. LU LET=45.	Date Code 9025	Date Code 9032	DC 9032, Table 2	No LU>100. 5/91 "=READ, **=WRITE	Compare following.	Perm. fall @ LET=60 IEEE92 Workshop p1	92IEEE Workshop Dufour 7/92	92IEEE Workshop Dufour 7/92 LU(th)<32; 3E-4 cm ² .	LU=58; 2E-4 cm ² . 92 IEEE Workshop Dufour. 7/92.	Compare earlier data.	No LU>87. Dufour 92IEEE Workshop	No LU>73. 7/92. Compare to next.	No LUs 120 7/92 Compare above.	5/91. No LU>120.	No LU>124. Dufour 92/EEE Workshop	No LU>87. 7/92 FSC design	No LUL-87, 7/92 FSC design
Facility***	88-In	BNF		BNL		BNL	BNL	N N	M	M		88-in	Nd	M	M	M	<u>₩</u>		Z	Z Z	CF-252	BNF	Nd.	Nd	N <u>d</u>	88-In		BNL	GANIL	GANIL	GANIL		GANIL	BNL	GANIL	BNL	GANIL	BNF	BNL
Cross Section Per Bit (sq µm)	1	8		9		ষ	12	88	12	8			4	4	8	4	8		ı	ı	ı	1		ı	ı	1		ı	ı	1	i		- (A	1	•	,	1	ı	1
Device Cross Section (cm²)***	0.15	1.25		0.11		0.24	1	1	1	ı		~2(4.5V)	1	1	1	1	•	(1)	: es:	i	2E-4(dyn.)	3E-3[dyn.]	ı	1	t	1E-4*	4E-4**	5E-3	0.2	5E-2	3. 1. 1. 1. 1. 1. 1. 1. 1. 1. 1. 1. 1. 1.		3E-5 (peripherals only)	. 1	75.6	1	> 3E-6	1.5E-5	AE.5
Effective LET** Threshold	က	Z		14		6.5	7	7	7-	7~		eş.	7	?	7	7	7	8 -		×114 ⁽¹⁾	6	Ę	ž	*54	1	~15*	24.6	3.4(wrthe)	<32	34	æ		8 3E	27.4	ಹ	8	110	•	4.5
Bits	128Kx8	512Kx8		1Mx1		1Mx1	4Mx1	4Mx1	4Mx1	4Mx1		1Mx4	4Mx1	4Mx1	4Mx1	4Mx1	4Mx1		PKXB	8Kx8	2Kx8	512x8	32Kx8	32Kx8	32Kx8	32Kx8		32Kx8	8Kx8	8Kx8	2Kx8		8Kx8	8Kx8	8Kx8	164/732	1	t	ì
Mr.	SNY	둪		E01		NEC	토	3	높	MCN		MCN	NEC	SAM	SIE	TMS	TOS		3	PLS	HIN	HTN	SEO	ATM	S	SEQ		SEQ	CYP	WAF	HAR		RAY	SGN	SGN	5	MTA	MTA	MTA
Technology	CMOS/NINOS	H-CMOS/epi 0.5 µm feature		1		ľ	ı	CMOS	CMOS	CMOS[1]		CMOS/epi 7 micron	CMOS	CMOS	CMOS	CMOS [EPIC]	CMOS		CHOS/SNOS	CMOS/SNOS	CMOS	CMOS/epi	CIMOS/FG	CMOS/FG	CMOS/FG	CMOS/epi	•	CMOS/epi	CMOS/FG	CMOS/FG	CINOS		Bipolar	Bipolar	Bipolar	CIMOS/epi			CMOS/epi
Function	SRAM	SRAM		DRAM		DRAM	DRAM	DRAM	DRAM	DRAM		DRAM	DRAM	DRAM	DRAM	DRAM	DRAM		MAM NOD-VOL	RAM Non-vol.	FRAM	FRAM	EEPROM	EEPROM	EEPROM	EEPROM		EEPROM	EEPROM	EEPROM	PROM		PROM	PROM	PROM	Bus Controller	MACS Bus Cont.	ASIC (Bus)	ASIC (Bus)
Device	CXK581001	HM628512	***************************************	EDI 41024C100QB	Mosaic	MDM1100TMB	Aosaic MDM1400G	MB814100-10PSZ	HM514100ZP8	MT4C1004C		MT4C4001	D424100V-80	KM41C4000Z-8	HYB514100J-10	TMS44100DM-80	TC514100Z-10		200	P1008	FMx1408	FMx1208	28HC258	28HC256	X28C256	DM28C256		28C256	CY7C261-55	WSF57C49B	HM6617		R29793DM	82HS641A	82HS641	UT 583		نے	Serial Cont.
Test Org.****	4	COD		Œ		Œ	Œ	ESA	ESA	ESA		⋖	ESA	ESA	ESA	ESA	ESA		CARS	CNES	7	-	CHES	CNES	CNES	⋖		COD	ş	Ş	MAKS		STEE STEE STEE STEE STEE STEE STEE STEE	CDD	MANS	-	MANS	g	99

TABLE 1. (Cont'd)

	ı		_																				;					1										
-	Chamile ESA Conf. 4450 als 111.00	Maillea Prince mountains	The roses. Dalour sziece Workshop See JPL data '87.	//st [1]=U flip-flop [2]=RAM config.	LU(th)=5; 5E-3 cm² DC9110 & 9045, 7/92	1991, ACT il family [1]=C module [~10 PLD-equivalent	gates.] [2]=S module. No LU>120. See Ref. 8	See Her. 8 [1]≍Process Prog. G A No LU>120.	See Ref. 8 No LUS 80.		See Ref. 8 No LU>120, 3/92 D F/F's; SRAM		5/91 [1]=Van de G.	6/91 [1]=Van de G.	6/91. Latchup.	No LU>120. 12/92	LU(th)<<26. 12/92	LU(th)=12: 5E-4 12/92	LU(th)=25; 3E-4 cm ² Die similar to below	Likihi-25: 3F-4 cm² Dia aimilar to atomic	6/92	6/92		LU(th)=25; 2E-3 cm ² .	No LU>100, 5/91 Compare preceding.	LU(th)=25; 5E-4 cm ² .	No LU>32. Dufour, 92 IEEE Workshop	NATION OF THE PROPERTY.	No LOSSE, Durour, 92 IEEE Workshop	No LUSTIG. Dufour, 92 IEEE Workshop ออลา	000	2629	707	No LUST40. Dufour, 92 IEEE Workshop	No LUST48. Durour, 92 IEEE Workshop	No LU>>37. DC8942 Wp-02 10/92	NO LUS 100, 1/91 NO LUS 100, 6/92	9/91. No LU>110.
Enellity	DANII	N V C	1 60		פאר	⊆	1		88-in		88-in		וואשוו	HAR[1]	Cf-252	BNF	BN	88-In	BNI	BNE	88-in	88-in		Z Z	BN,	BK BK	GANIL	III O		GANIL Be.in		5 2		GANIL	GANIL Service	מאר ה	88-in	88-in
Cross Section Per Bit (set 11m)		,	4000141	[1]0071	-	sw[1]	8000[2]	2	9		<u>2</u>		ı	ı	ı	1	ı	ı	ı	ı	ı	ı		ı	t	1	-	2500	360	5000				ŧ	ı	ı	l i	
Device Cross Section (cm²)***	2E-3	55.3	<u>}</u>	l	į .	ı	1	Ĭ	•		ı	2 6E 6(ant)	or con	3E-0(881)	4.ZE-5	ı	ı	1	7E-6	1E-5	2E-5	2E-5		1	<1E-7	<u>1</u> 64	1E-3	17.	15.5	7 7	25-5/1 ET-10)	>2E-5(1 FT=10)	SE e	0-30	3 13 0	5.0E-5	4E-5	2E-3
Effective LET** Threshold	<5.5	8	8	j i	30(1)		<u>7</u> 8	3	\$;	8	7.4	;	9		120	ı	ro.	1 0	ın	4	4	ţ	=	×100	IO.	7	,	. 69	, 6				346	ę	3 F,	ន	9
魏		:	Multicali	ı	120		38K gates		Test Chip			ı	1	I	ı	í	ı	1	ı	1	1	ı		ı	1	ı	'	4	4	~ ~	:	•	ı		Ceta	Octal	8	
Mr.	뜐	MTA	NOH	×	ACT		3		M 15	Ē	Ē	ALT	T IA	SEO SE	3 5	5	a (cy P	CYP	MMI	AMD	¥	Ę	<u> </u>	<u> 101</u>	AMD	¥	ΧIT	MOT	MOT	NSC	SGN	MOT	₽	NSC	Ě	HAR/GE	SLG
Technology		.) CMOS	RICMOS III	CMOS	CMOS/epi (1.2 um	(nathira)	CMOS/epi rad-hard	(1.5 µm feature)	CMOS/epi rad-hard	(1.5 µm feature)	(1.0 µm feature)		1		BICHOS		5000	CMOS	CMOS	CMOS	Bipolar	Bipolar	CMOS	9010	CMOS	S CINOS	LSI I.	lsПL	blpolar/ECL	TT(LS)	bipolar	blpolar	FACT	FACT		CMOS/HCT	CMOS/HCT	bipolar (&1 JFET)
Function	ASIC (Bus)	Gate Array (Memory Plan.)	Gate Array	FPGA	FPGA		PPGA[1]		PPGA	P DG A	5	Prog. Logic Dev.	22	PLD	. IVd	īVā	, e	į :	PAL	PAL	PAL	PAL	EDAC (32-bit)	EDAC (SOLE)	EDAC (32-0ft)	EDAC (32-011)	EUAC	D-FF	P. FF	J-K/FF	Timer	Timer	Counter	DFF	D-Latch	Latch	Counter	MWd
Device	-		HR1060	XC3090	A1280		LRH10038Q		HP03	RA20K		EP310	EP600	20RA10Z	22V10C-10	22V10D.15DMR	22V10B	20145	01,77	22410	22V10A	ZZV10A	IDT49C460	INTAGCAGA	2000	EAI Cean	2412620	54LS74A	MC10531	541.5112	555	555	54ACT163	54ACT374	54ACTQ373	54HCT373	54HCT393	PWM1526
Test Org.****	CNES	S	<u>₹</u>	GDD	⋖		⋖		∢	⋖	:	ESA	ESA	ESA	CDD			. 2		Ē.	⋖ '	∢	BM	•	. 2			MANS	SWE S	⋖	BPS	BPS	SE SE	MINS	NOH HO	⋖	V	~

TABLE 2. LATCHUP TEST ONLY (1991-1992)

																o earlier data.		ns & Table 1.											JS IV (J; 7/91).												
	Remarks	1750A CPU.	4/91	12/91	1291	12/91	May 91. Table 1. MIPS RISC. D. Vall (HAR)	May 91. Table 1. MIPS RISC. D. Vail (HAR)	May 91. Table 1. MIPS RISC. D. Vall.	May 91. Table 1. MIPS RISC. D. Vail.	SPARC. Dufour, 92 IEEE Workshop	SPARC. Dufour, 92 IEEE Workshop	SPARC. Dufour, 92 IEEE Workshop	Dufour, 92 IEEE Workshop	June 1992	LU=26 at 125 deg. C 5/91, DC 8939, Compare to earlier data.	See Table 1.	92 IEEE Workshop, Kinnison. 7/92. See previous & Table 1.	12/92. Compare to IEEE 91	6/92	4/91. Dynamic test. See also Table 1.	IEEE NS (Dec 91) p 1398. See below.	92 IEEE Workshop Dufour 7/92	4/90	92 IEEE Workshop Dufour 7/92	6/92	DC 8942 Compare to 68882 below.	DC 9022. compare to 68881 above.	9/91. *Deduced from INT 80386 Table 1, CHMOS IV (J; 7/91).	10/92. See Table 1.	7/92	11/92. Up to 125°C.	Aug 91 See following entry.	Aug 91 See preceding entry.	Jun 92	7/92. T.C. Lunn	7/92. T.C. Lunn	4/92	10/92	10/92 (DC9022)	11/92
	Facility***	BN	BNL	88-in	88-in	88-in	H H H	BNL	BN	BNL	GANIL	GANIL	GANIL	GANIL	88-in	BNL			88-in	BNL	BNF	Z Z	GANIL	BNL	GANIL	BNL	M	N.	88-in		BNI	BNL	N	N <u>d</u>	88-in	BN	EN EN	CI-252	CI-252	CI-252	BNE
Cross	(cm²)**	1	1	4E-6	2E-3	2E-5	ı	1	ı	1	4E-3	5E-2	2E-3	×1E-4				1	5E-5	ı	ı	<u>1</u>	1E-3	ı	ı	2E-3	4E-3	1E-3	3E-5*(sat)	1	4E-5(sat)	ı	5E-4	2E-3	ı	>>3E-5		<u>^</u>	1	1	
Effective LET**	Threshold	Į2	32+6	18	16	8	4.8	88	8	ន	16.5	8.2	2	45	17	36 @ 1E5 lons/cm ²	,	8	5	69⊀	12	5	8	35	<30	5	မှ	12	8	24 to 37	ಸ	>120	~30	12	×100	? [LET=60]	9**	**30	**30	**30	
	Bits	1	1	1	•	ı	•	ı	1	1	1	ŧ	1	:	1	1		ı		ı	1	ı			1	1	Custom	Custom	all 640	all 640	all 640	1		1	ı	ı	1	ı	1	1	
	Mr.	SI	MOT	HAR	HAR	HAR	TOI	TOI	PFS	ısı	ısı	IS.	ısı	WN.	ATT	TIX (France)		¥	ΧĽ	ΧĽ	MOT	ADI	ADI	둗	ADI	AMD	MOT	MOT	M	¥	¥	Satt	TINS	TINS SWIT	MPS	BUB	SIP	SIP	LTC	HAR	
	Technology	CMOS/epi	CMOS/epi	CMOS	CINOS	CMOS	CMOS?	CMOS?	CMOS?	CMOS	CMOS/epi	CMOS	CMOS/epi	CMOS	CMOS	CMOS/epi	•	New CMOS/epi	CMOS/epi 7 µm	CMOS/epi	CMOS	CMOS/epi 18 µm	CMOS/epi	. 1	CMOS/epi	CMOS	HCMOS/bulk 1.5 µm	HCMOS/bulk 1.2 µm	CHIMOS IV	CHMOS IV	CHMOS IV	CMOS	CMOS (HS13)	CMOS (HCMOS3)	CMOS	Hybrid? DC: 8920/9128	Hybrid? DC: 9203	CMOS	CMOS	BICMOS	1
	Function	MicroP (16-bit)	MicroP (16-bit)		To ller				_	MicroP (32-bit)		_	F.P.U. (32-bH)	Transputer (32-bit)	DSP	DSP		DSP 6 µm epi	DSP	DSP	DSP	DSP (16-bit)	DSP (16-bit)	DSP (16-bit)	DSP (16-bit)	MicroC.	Coprocessor	Coprocessor	Coprocessor	Coprocessor	Coprocessor	8-bit ADC (Flash)	8-bit ADC	8-bit ADC	10-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	12-bit ADC	
	Device	64500/1	68020	HS82C88	HS82C59A	HS82C52	H3000	R3000A	R3000A	H3000	L64801	L64811	L64814	1800	WE-DSP32C	320C25		320C25	320C30	320C50	56001	ADSP2100A	ADSP2100A	ADSP2100	ADSP2100	AM29CEPL154	68881	68882	80397	80387-16	80387	MP7684/MP7684A	TMS8338	TMS8338	MP7695	ADC87	ADC85	SP7800	LTC1272	HI774B	
Test	Org.****	=	2	<	<	: ∢	HAR	HAR	HAR	HAR	SES	MMS	MMS	MMS	4	7		독	∢	7	3	=	MANS	픙	MMS	7	CNES	CNES	7	GE ,	dop /	7	CNES	CNES	<	THW	TRW	~	7	7	

^{*} See listing of abbreviations in Appendix I.

** LET is Linear Energy Transfer = the density of konization along an ion's path in MeVi(mg/cm²). The cosine law for beam angle is applied where valid to obtain "effective" LET.

**** See listing of abbreviations in Appendix II.

***** See listing of abbreviations in Appendix II.

***** See listing of abbreviations in Appendix II.

***** Unless otherwise noted, the cross section (upsets/fluence per device) is given for 240-380 MeV Kr or Br at normal incidence, having an LET=36 to 40 MeV/(mg/cm²).

TABLE 2. (Cont'd)

Device

Effective Conne

- P	nomera	4/91	1/92. Compare JH: Aerospace date [5/90]	5/91. See above.	11/92. Up to 125 °C.	11/92. Up to 125 °C.	Dufour, 92 IEEE Workshop	Kinnison 4/92	Kinnison 4/92	See Table 1.	92 IEEE Workshop Dufour 7/92	4/94 SEE Symb. High Temp data exists.	Chapuls, at ESA Conf. 11/90	92 IEEE Workshop Dufour 7/92. See Table 1.	92 IEEE Workshop Dufour 7/92. See Table 1.	IEEE '92. Proton LU also occurs.	April '91	Sferrino '91	Sferrino '91 Compare above.	Compare Table 1, 92 IEEE Workshop Dufour, 7/92	Sferrino '91	DC 9109	Sterrino '91	Date Code 9032	Sferrino '91	Sferrino '91	92 IEEE Workshop Dufour 7/92	DC 9109 [1] = 547 logic modules. 4 ports/module. confin amilties	92 IEEE Workshop Dufour 7/92	92 IEEE Workshop Dufour 7/92	92 IEEE Workshop Dufour 7/92	10/92	CSC	26/20 PA	9/9/2 saturated SEII-2E-8 cm2	LIN: 1991: S ² : 1999	June 1991	92 IEEE Workshop Dufour 7/92	92 IEEE Workshop Dufour 7/92	392	1292	1292	1/91 NSC's FACT DC>8826 are designed LU-proof	4/91	7/91
Enclishess	, man	JAB	EN L	88-in	BNL	NA BN	GANIL	- A	NA NA	BN	GANIL	CI-252	<u>M</u>	GANIL	GANIL	Harwell	BNL	M L	BNL BNL	GANIL	BNL	M	BNL	M	BNL	BNL	GANIL	PN	GANIL	GANIL	GANIL	88-in	110			NE NE	88-in	GANIL	GANIL				BNL		98-in
Cross Section) III.	1	1	5E-3	1	1	1		ı	1	ı	8E-5		1	ı	0.15[LET=12]	,	ı		#4	1	1		1E-3	ı		1	_	ı	ı		1E-6			. 1		8E-5	ı		1	,	3E-4	ı		3E-4
Effective LET**		8	<<12	ŧ	×120	×120	>116	15	5	8	×140	*	<55	>140	×140	~	F3	<u>*</u>	38 to 69	ĸ	<27	>54	>164	18	×164	×164	×18	>27	08 4	<36		51 to 80	120	8	×120	ន		×137	×137	×100	×100		×120		ន
e #			ı	1	1	ı	ı	8Kx87	1Kx9?	1Kx9	1Kx9	ЭКХВ	8Kx8	8Kx8	32Kx8	2 4	2Kx8	32Kx8	32Kx8	128Kx8	32Kx8	1Mx4	9Kx8	32Kx8	32Kx8	8Kx8	8Kx8	,	ı	ı	ı	ı	None	e con	None	None	ı	Quad	Dual	ı	ı	1	ı	ı	1
		DAT	CRY	CHY	ADI	MPS	SOR	TOI	ΙQΙ	TQ1	MTA	СУР	MTA	MTA	MTA	NEC	S S	¥Ç.	¥CN	¥CN	토	¥CN	RAY	XIC	SEQ	SEO	3	TIX[1]	MTA	MED	TRW	ADA	HAR	NSC	HAR	NSC	LTC	SIL	SIL	SIL	HAR	LTC	NSC	PFS	ZYR
Technology			CMOS	CMOS/epi	CMOS	CMOS	CMOS	CMOS	CMOS	CMOS/epi	SCMOS/epi RT	CMOS	CMOS/epi	SCMOS/epi RT	SCMOS/epi RT	CMOS		CMOS/epi	CMOS	CMOS/bulk	CMOS	CMOS/epl 0.8 µm epl	CMOS/epi? fuse-link	CMOS/FG	CMOS/epi	CMOS/epi?	Bipolar	CMOS/epi	SCIMOS/epi RT	CMOS	CMOS	CMOS	CMOS/SOS	CMOS	CMOS/SOS	CINOS	CMOS	CMOS	CINOS	CMOS/epi 13 microns	CMOS	CMOS	FACT W. I/O	CMOS	CMOS
Function		12-bit ADC	16-bit ADC	16-bit ADC	10-bit DAC	10-bit DAC	12-bit DAC	E E	얦	얦	댎	SRAM	SRAM	SHAM	SHAM	SRAM	SHAM	SHAM	SHAM	SHAM	SRAM	DRAM	SROM	EEPROM	EEPROM	EEPROM	PROM	FPGA	GA 35K	1553 Bus Cont.	Mult./Accum.	DC/DC Conv. module	Driver	Driver	Receiver	Receiver	Transceiver	Analog Switch	Analog Switch	Analog Switch	Analog MUX	Low Pass Filter	Logic	egic S	SAR
Device		ADS112	CS5016	CS5016	AD7533	MP7533	S0R7541	734RT	7202HT	7202RE	M67202	CYC185	HM65641	HM65654	HM65656	D4464D	M15C7608	M15C2568	MT5C2568	MISCHOOLECAN	DPS92256G	M14C1004C	R29793	X28C256	28C256	28064	MB7144E	1020A	MC5000	MA805		AIWZBKK	26C31	26C31	26C32	26C32	LTC485CN8	DG271	DG300	DG601AK	IH6208	LTC:1064	54AC10244	PSETC1245	\$012ES
Test Org.****		S	SSS	⋖ '	-	- >	SE SE	5 :	5		SS	8	CNES	NAMES.		ESA.	£ :	3 :			N	CNES		CNES	<u>.</u>	<u> </u>	MMS	CNES		QUINT.	SWW.	<		LN	-	LINSSS		S .	MMS	⋖ •	⋖ •		5 =		ξ.

TECHNOLOGY OPERATIONS

The Aerospace Corporation functions as an "architect-engineer" for national security programs, specializing in advanced military space systems. The Corporation's Technology Operations supports the effective and timely development and operation of national security systems through scientific research and the application of advanced technology. Vital to the success of the Corporation is the technical staff's wide-ranging expertise and its ability to stay abreast of new technological developments and program support issues associated with rapidly evolving space systems. Contributing capabilities are provided by these individual Technology Centers:

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Mechanics and Materials Technology Center: Evaluation and characterization of new materials: metals, alloys, ceramics, polymers and composites; development and analysis of advanced materials processing and deposition techniques; nondestructive evaluation, component failure analysis and reliability; fracture mechanics and stress corrosion; analysis and evaluation of materials at cryogenic and elevated temperatures; launch vehicle fluid mechanics, heat transfer and flight dynamics; aerothermodynamics; chemical and electric propulsion; environmental chemistry; combustion processes; spacecraft structural mechanics, space environment effects on materials, hardening and vulnerability assessment; contamination, thermal and structural control; lubrication and surface phenomena; microengineering technology and microinstrument development.

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